

L Number	Hits	Search Text	DB	Time stamp
-	3117	324/765	USPAT	2003/12/22 09:38
-	1428	324/765 and wafer	USPAT	2003/06/04 11:07
-	203	(324/765 and wafer) and sensor	USPAT	2003/06/04 11:07
-	136	((324/765 and wafer) and sensor) and probe	USPAT	2003/06/04 11:07
-	39	((324/765 and wafer) and sensor) and probe) and chamber	USPAT	2003/06/05 12:37
-	37	((324/765 and wafer) and sensor) and probe) and chamber and semiconductor	USPAT	2003/06/05 13:22
-	22	((324/765 and wafer) and sensor) and probe) and chamber and semiconductor) and air	USPAT	2003/06/05 13:23
-	2218	324/765 and semiconductor	USPAT	2003/06/05 14:56
-	0	(324/765 and semiconductor) and "process\$4 chamber"	USPAT	2003/06/05 13:45
-	25	(324/765 and semiconductor) and "processing chamber"	USPAT	2003/06/05 13:45
-	24	((324/765 and semiconductor) and "processing chamber") and wafer	USPAT	2003/06/05 13:45
-	10	((324/765 and semiconductor) and "processing chamber") and wafer) and probe	USPAT	2003/06/05 14:55
-	364	(324/765 and semiconductor) and module	USPAT	2003/06/05 14:56
-	49	((324/765 and semiconductor) and module) and sensor	USPAT	2003/06/05 14:56
-	37	((324/765 and semiconductor) and module) and sensor) and wafer	USPAT	2003/06/05 14:58
-	23	((324/765 and semiconductor) and module) and sensor) and wafer and probe	USPAT	2003/06/05 14:59
-	323	324/765 and "silicon substrate"	USPAT	2003/06/05 15:10
-	179	(324/765 and "silicon substrate") and probe	USPAT	2003/06/05 15:01
-	0	((324/765 and "silicon substrate") and probe) and luminescent	USPAT	2003/06/05 15:01
-	56	((324/765 and "silicon substrate") and probe) and light	USPAT	2003/06/05 15:02
-	0	324/765 and "wafer sensor module"	USPAT	2003/06/05 15:10
-	10	324/765 and "wafer sensor"	USPAT	2003/06/05 15:11
-	6	324/765 and "wafer sensor" and silicon	USPAT	2003/06/05 15:11
-	5	(324/765 and "wafer sensor" and silicon) and probe	USPAT	2003/06/05 15:12
-	0	((324/765 and "wafer sensor" and silicon) and probe) and luminescent	USPAT	2003/06/05 15:12
-	0	((324/765 and "wafer sensor" and silicon) and probe) and lumines\$4	USPAT	2003/06/05 15:12
-	2	((324/765 and "wafer sensor" and silicon) and probe) and light	USPAT	2003/06/05 15:12
-	1758	324/765.ccls.	USPAT	2003/12/22 09:38
-	210	324/765.ccls. and chamber	USPAT	2003/12/22 09:38
-	67	324/765.ccls. and chamber and stage	USPAT	2003/12/22 09:38
-	19	324/765.ccls. and chamber and stage and sensor	USPAT	2003/12/22 09:38
-	6	324/765.ccls. and chamber and stage and sensor and module	USPAT	2003/12/22 09:38
-	5	324/765.ccls. and chamber and stage and sensor and module and probe	USPAT	2003/12/22 09:39
-	5	324/765.ccls. and chamber and stage and sensor and module and probe and current	USPAT	2003/12/22 09:39

-	3	324/765.ccls. and chamber and stage and sensor and module and probe and current and voltage	USPAT	2003/12/22 09:39
-	1	324/765.ccls. and chamber and stage and sensor and module and probe and current and voltage and temperature	USPAT	2003/12/22 09:39